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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto Art Unit : 1765
Serial No. : 10/689,617 Examiner : Lan Vinh
Filed : October 22, 2003
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING
SEMICONDUCTOR DEVICE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL AMENDMENT

Prior to examination, please amend the application as indicated on the following pages.